In the Specification:

On page 13, please amend the first full paragraph to read as follows:

The fourth aspect of the invention is method of manufacturing a semiconductor light emitting device by growing nitride III-V compound semiconductor layers forming a light emitting device structure on a nitride III-V compound semiconductor substrate in which a plurality of second regions having a second average <u>dislocation_defect</u> density higher than a first average <u>dislocation_defect</u> density align regularly in a first region made of a crystal and having the first average <u>dislocation_defect</u> density, comprising:

On pages 13-14, please amend the paragraph bridging pages 13 and 14 as follows:

The fifth aspect of the invention is a semiconductor light emitting device manufactured by: growing nitride III-V compound semiconductor layers forming a light emitting device structure on a nitride III-V compound semiconductor substrate in which a plurality of second regions having a second average dislocationdefect density higher than a first average dislocationdefect density align regularly in a first region made of a crystal and having the first average dislocationdefect density; and